

Amendments to the Claims:

The following listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) ~~A material arranging method of arranging a material forming a plurality of films on a base, the method comprising:~~

~~ejecting the material from setting a plurality of relative positions of at least one nozzle toward a predetermined area of to the base, which is provided in a vacuum atmosphere that is adjusted to a high degree of vacuum~~

~~the setting the plurality of relative positions including moving at least one of the at least one nozzle and the base;~~

~~ejecting a first gasified material from the at least one nozzle toward the base at each of the plurality of relative positions; and~~

~~detecting an ejection failure of a the at least one nozzle in the vacuum atmosphere before starting the ejection step.~~

2. (Currently Amended) ~~A material arranging~~ The method of arranging a material on a base, the method comprising: according to Claim 1,

~~ejecting the material from at least one nozzle toward a predetermined area of the base, which is being provided in a vacuum atmosphere that is adjusted to a pressure of 10^{-3} torr or less; and~~ during at least a period in which the ejecting the first gasified material is carried out.

~~detecting an ejection failure of a nozzle in the vacuum atmosphere before starting the ejection step.~~

3. (Currently Amended) ~~A material arranging~~ The method of arranging a material on a base, the method comprising: according to Claim 1,

~~ejecting the material from at least one nozzle toward a predetermined area of the base, which is being~~ provided in a vacuum atmosphere that is adjusted to a pressure of 10^{-5} torr or less; and during at least a period in which the ejecting the first gasified material is carried out.

~~detecting an ejection failure of a nozzle in the vacuum atmosphere before starting the ejection step.~~

4. (Currently Amended) The ~~material arranging method~~ according to Claim 1, ~~the detecting an the ejection failure of at least one nozzle further including an action of ejecting the material to a preliminary ejecting area other than the predetermined area and detecting the ejection failure of a nozzle on the basis of the ejecting result~~ ejection of the first gasified material to a preliminary-ejecting area provided in a preliminary member provided in a predetermined area on the base, and

the plurality of films being to be formed in the predetermined area.

5. (Currently Amended) The ~~material arranging method~~ according to Claim 1, ~~the detecting an the ejection failure further of at least one nozzle including an action of providing a preliminary member in the predetermined area, ejecting the material to a preliminary ejecting area provided in the preliminary member, and detecting the ejection failure of a nozzle on the basis of the ejection result~~ ejection of the first gasified material to a preliminary-ejecting area provided in a preliminary member in a predetermined area on the base, and

the ejection failure being detected on the basis of an inspection of a preliminary film that is formed on the preliminary-ejecting area by the preliminary ejection.

6. (Currently Amended) The ~~material arranging method~~ according to ~~Claim 4~~ Claim 5, ~~detecting an ejection failure of a nozzle~~ the inspection of the preliminary film being

performed by ~~detecting a~~ a measurement of light-reflectivity of ~~the material ejected to the~~
preliminary-ejecting-area film.

7. (Currently Amended) The ~~material arranging-method~~ according to ~~Claim 4,~~
Claim 5, detecting the ejection failure of the at least one nozzle the inspection of the
preliminary film being performed by ~~detecting a~~ a measurement of light-transmissivity of ~~the~~
material ejected to the preliminary-ejecting-area film.

8. (Currently Amended) The ~~material arranging-method~~ according to Claim 1,
further comprising ejecting a second gasified material from the at least one nozzle,
the detecting the an ejection failure being performed at the time of changing of
the material in the ejection step of the at least one nozzle being carried out prior to the
ejecting the second gasified material from the at least one nozzle.

9. (Currently Amended) ~~A material arranging method of arranging a material on~~
~~a base, the method comprising:~~ A method of forming of plurality of films, the method
comprising:

setting a first relative position of at least one nozzle to the base, the setting the
first relative position including moving at least one of the at least one nozzle and the base;

ejecting a first gasified material to a first area of the base from at least one
nozzle at the relative position, the plurality of films being to be formed in the first area; and

setting a second relative position of the at least one nozzle to the base, the
setting the second relative position including moving at least one of the at least one nozzle
and the base; and

ejecting the first gasified material to a second area of the base other than the
first area from the at least one nozzle at the second position,

the ejecting the first gasified material to the second area being carried out prior
to the ejecting the first gasified material to the first area.

~~_____ejecting the material from at least one nozzle toward a predetermined area of the base, which is provided in a vacuum atmosphere that is adjusted to a high degree of vacuum; and~~

~~_____preliminarily ejecting the material from a nozzle toward an area on the base other than the predetermined area before starting the ejection step.~~

10. (Currently Amended) A material arranging method of arranging a material on a base, the method comprising: The method according to Claim 9,

the base being provided in a vacuum atmosphere during at least a period in which the ejecting the first gasified material to the first area is carried out.

~~_____ejecting the material from at least one nozzle toward a predetermined area of the base, which is provided in a vacuum atmosphere that is adjusted to a pressure of 10^{-3} torr or less; and~~

~~_____preliminarily ejecting the material from a nozzle toward an area on the base other than the predetermined area before starting the ejection step.~~

11. (Currently Amended) A material arranging method of arranging a material on a base, the method comprising: The method according to Claim 9,

the base being provided in a vacuum atmosphere that is adjusted to 10^{-3} torr or less during at least a period in which the ejecting the first gasified material to the first area is carried out.

~~_____ejecting the material from at least one nozzle toward a predetermined area of the base, which is provided in a vacuum atmosphere that is adjusted to a pressure of 10^{-5} torr or less; and~~

~~_____preliminarily ejecting the material from a nozzle toward an area on the base other than the predetermined area, before starting the ejection step.~~

12. (Canceled)

13. (Currently Amended) The ~~material-arranging method~~ according to Claim 9, ~~further comprising the preliminary ejection step being performed at the time of changing the material in the ejection step.~~

ejecting a second gasified material to the first area of the base from the at least one nozzle; and

ejecting the second gasified material to the second area,

the ejecting the second gasified material being carried out prior to the ejecting the second gasified material.

14. (Currently Amended) The ~~material-arranging method~~ according to Claim 9, ~~further comprising a detecting an arranged position of the material arranged through the preliminary ejection and a target position to arrange the material through the preliminary ejection right after the preliminary ejection step, and performing a positional correction of a nozzle when a positional deviation occurs between the arranged position and the target position.~~

a positional deviation between a first position where a preliminary film is to be formed by ejecting the first gasified material to the second area and a second position where the preliminary film is actually formed in the second area by the ejecting the first gasified material to the second area being detected, and

a positional correction of the at least one nozzle being carried out when the positional deviation is observed.

15. (Currently Amended) A method of manufacturing an electronic device, at least ~~some one element of~~ elements constituting the electronic device being formed using the ~~material-arranging method~~ according to Claim 1.

16. (Currently Amended) The method ~~of manufacturing an electronic device~~ according to Claim 15, the first gasified material being for forming at least one layer of a

conductive layer, a semiconductor layer, and an insulating layer ~~constituting a transistor or a memory element being arranged as the material, and then the conductive layer, the semiconductor layer, or the insulating layer is formed.~~ of the at least one element.

17. (Currently Amended) The method ~~of manufacturing an electronic device according to Claim 15, patterns that separate wires from each other being formed in advance on the base, the forming material being arranged in the patterns, and then the conductive layer being formed.~~ further comprising providing a pattern prior to the ejecting the first gasified material,

the plurality of films being formed the pattern by the first gasified material.

18. (Currently Amended) A method of manufacturing an electro-optical device, at least some elements ~~constituting the electro-optical device being formed using the material~~ arranging including a plurality of electro-optical elements, the plurality of electro-optical elements being formed using the method according to Claim 1.

19. (Currently Amended) The method ~~of manufacturing an electro-optical device according to Claim 18, a material that forms at least one of an electron-transporting layer, a hole-transporting layer, a light-emitting layer, and electrodes constituting an organic electroluminescent element being arranged as the material, and then the electron-transporting layer, the hole-transporting layer, the light-emitting layer, or the electrodes being formed.~~

the plurality of electro-optical elements being a plurality of organic electroluminescent elements each of which includes an electron-transporting layer, a hole-transporting layer, a light-emitting layer, and electrodes, and

the first gasified material being used for at least one of the electron-transporting layer, the hole-transporting layer, the light-emitting layer, and the electrodes.

20. (Currently Amended) The method ~~of manufacturing an electro-optical device according to Claim 18, partitions that separate pixels from each other being formed in~~

~~advance on the base, the forming material being arranged in the partitions, and then the electron-transporting layer, the hole-transporting layer, or the light-emitting layer being formed.~~Claim 19, further comprising forming partitions that separate pixels from each other which are to be formed after the forming the partitions and each of which corresponds to one of the plurality of electro-optical elements,

at least the light-emitting layer among the electron-transporting layer, the hole-transporting layer, and the light-emitting layer being formed on are surrounded by the partitions.

21. (Withdrawn) A film-forming apparatus comprising:

a processing chamber;

a pressure control system that controls a pressure in the processing chamber to a low pressure;

at least one nozzle provided in the processing chamber and connected to a material supply source, that arrange a material on a member provided in the processing chamber;

a stage provided in the processing chamber that holds a member;

a moving device that relatively move a position of the nozzle or the stage; and

an inspecting device that inspects the material arranged on the member.

22. (Withdrawn) A film-forming apparatus comprising:

a processing chamber;

a pressure control system that controls a pressure in the processing chamber to a low pressure;

a head having a plurality of nozzles provided in the processing chamber and connected to a material supply source, that arrange a material on a member provided in the processing chamber;

a stage provided in the processing chamber that holds the member;
a moving device that relatively moves a position of the nozzles or the stage;
and

an inspecting device that inspects the material arranged on the member.

23. (Withdrawn) The film-forming apparatus according to Claim 21, the member being a base having a predetermined area in which a film of the material is formed.

24. (Withdrawn) The film-forming apparatus according to Claim 21, the member being a preliminary member having a preliminary-ejecting area.

25. (Withdrawn) The film-forming apparatus according to Claim 21, the nozzles further including a preliminary nozzle to be used in place of a nozzle having an ejection failure, when the ejection failure occurs in one of the nozzles.

26. (Withdrawn) The film-forming apparatus according to Claim 21, the inspecting device including a detecting device for detecting an ejection failure of the nozzles on the basis of an ejecting result of the material.

27. (Withdrawn) The film-forming apparatus according to Claim 21, the inspecting device further comprising a position correcting device that detects an arranged position of the material and a target position to arrange the material and performing a positional correction of the nozzles when a positional deviation occurs between the arranged position and the target position.

28. (Withdrawn)) An electronic device manufactured using the film-forming apparatus according to Claim 21.

29. (Withdrawn)) An electro-optical device manufactured using the film-forming apparatus according to Claim 21.

30. (Withdrawn) An electronic apparatus comprising the electro-optical device according to Claim 29 as a display device.

31. (New) The method according to Claim 1,
the detecting an ejection failure of the at least one nozzle being carried out
using a sensor.
32. (New) A method of forming a plurality of films on a base, the method
comprising:
setting a plurality of relative positions of at least one nozzle to the base, the
setting the plurality of relative positions including moving at least one of the at least one
nozzle and the base;
ejecting a first gasified material from the at least one nozzle toward the base at
each of the plurality of relative positions; and
sensing at least one film of the plurality of films by a sensor.
33. (New) The method according to Claim 32,
the sensing the at least one film including an irradiation of the at least one film
with a light source.
34. (New) The method according to Claim 32,
the sensor measuring at least one of a transmission light that transmits the at
least one film and a reflection light that is reflected by the at least one film.
35. (New) The method according to Claim 32,
the base being provided in a vacuum atmosphere that is adjusted to 10^{-3} torr or
less during at least a period in which the ejecting the first gasified material is carried out.
36. (New) A method of forming a plurality of films on a base, the method
comprising:
ejecting a first gasified material from a nozzle of a plurality of nozzles and a
second gasified material from a nozzle of the plurality of nozzles; and
sensing at least one film of the plurality of films by a sensor,

the plurality of nozzles moving during at least a part of a period in which the method is carried out.

37. (New) A method of manufacturing an electronic device, at least one element of elements constituting the electronic device being formed using the method according to Claim 32.

38. (New) A method of manufacturing an electronic device, at least one element of elements constituting the electronic device being formed using the method according to Claim 36.

39. (New) A method of manufacturing an electro-optical device including a plurality of electro-optical elements, the plurality of electro-optical elements being formed using the method according to Claim 36.

40. (New) The method according to Claim 39,
the plurality of electro-optical elements being a plurality of organic electroluminescent elements each of which includes an electron-transporting layer, a hole-transporting layer, a light-emitting layer, and electrodes,
the first gasified material and the second gasified material being used for at least one of the electron-transporting layer, the hole-transporting layer, the light-emitting layer, and the electrodes, and
the formation of the light-emitting layer including a co-evaporation process.

41. (New) A method of manufacturing an electro-optical device including a plurality of electro-optical elements, the method comprising:
ejecting a first gasified material from a nozzle of a plurality of nozzles and a second gasified material from a nozzle of the plurality of nozzles,
the plurality of nozzles moving during at least a period in which the ejecting the first gasified material and the second gasified material,

the plurality of electro-optical elements being a plurality of organic electroluminescent elements each of which includes an electron-transporting layer, a hole-transporting layer, a light-emitting layer, and electrodes,

the first gasified material and the second gasified material being used for at least one of the electron-transporting layer, the hole-transporting layer, the light-emitting layer, and the electrodes, and

the formation of the light-emitting layer including a co-evaporation process.

42. (New) A method of forming a plurality of films on a base, the method comprising:
ejecting a first gasified material from the at least one nozzle toward the base at each of a plurality of relative positions; and

sensing at least one film of the plurality of films by a sensor,

a scanning movement of the at least one nozzle being carried out during at least a part of a period in which the method is carried out.

43. (New) A method of forming a plurality of films on a base, the method comprising:
ejecting a first gasified material from a nozzle of a plurality of nozzles and a second gasified material from a nozzle of the plurality of nozzles; and

sensing at least one film of the plurality of films by a sensor,

a scanning movement of the plurality of nozzles being carried out during at least a part of a period in which the method is carried out.

44. (New) The method according to Claim 36,
the plurality of nozzles being provided in a discharge head.

45. (New) The method according to Claim 44,

the discharge head moving along at least one of X-coordinate, Y-coordinate, and Z-coordinate during at least a part of a period in which the method is carried out.

46. (New) The method according to Claim 44,
the discharge head rotating during at least a part of a period in which the method is carried out.

47. (New) The method according to Claim 1,
the base being provided in a vacuum atmosphere during at least a period in which the ejecting the first gasified material is carried out.

48. (New) A method of forming a plurality of films on a base, the method comprising:

detecting an ejection failure of a first nozzle;

setting a first relative position of the first nozzle to the base, the setting the relative position including moving at least one of the first nozzle and the base;

ejecting a first gasified material from the first nozzle toward the base at the first relative position;

detecting an ejection failure of a second nozzle;

setting a second relative position of the second nozzle to the base, the setting the relative position including moving at least one of the second nozzle and the base; and

ejecting a second gasified material from the second nozzle toward the base at the second relative position.